



तमसो मा ज्योतिर्गमय

DEPARTMENT OF MATERIAL SCIENCE AND ENGINEERING
NITC CALICUT



**JOB REQUISITION FORM FOR MULTISOURCE PHYSICAL VAPOUR
DEPOSITIONSYSTEM**

Name:		Designation:
Address: (Institution/Department)		Contact number:
		Email ID:
Supervisor:		Contact number:
		Email ID:
Internal (NITC)/External/Industry		
Number of depositions		
Is Co-deposition required? (tick any one)		: YES/NO

Technical Details:

DC / RF power required	
Sputtering Distance / Time	
Substrate Cleaning	Required/ Not Required
Gas flow rate (Ar)	

PVD Source	Description of Material to be deposited	Description of Substrate material	Desired film thickness (Limited to 200- 300 nm)	Co-sputtering/Co-evaporation required, if yes mention the different materials
Thermal Evaporation				
RF Magnetron Sputtering				
DC Magnetron Sputtering				



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This work is part of the research activity of the department / center. No remuneration or compensation is received from any agency. Further, it is certified that the sample(s) do not pose a health risk to anybody.

Date: _____ **Signature of Researcher**

Recommendation of Supervisor _____ :

Signature of the Head of the Dept/Institution _____ :

For laboratory use:	
Job priority: high/medium/low Ref no:	Date and time allotted:
Job completed on date:	Remarks:
Signature of faculty in-charge	
Approval	Director,

For office use

Ref. No: _____

Date: _____

Name and institution of the user				
Deposition (Technique)				
Deposition charges				
Payment details	DD/Cheque no.	Date	Bank name	Amount
Name of the faculty who conducted the experiment				